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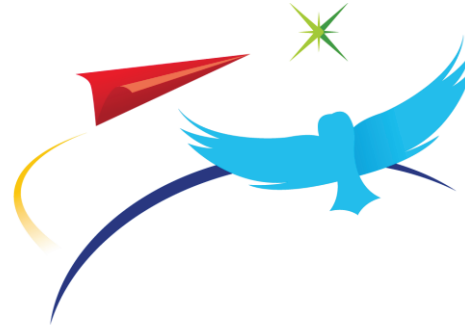
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CENTRE NATIONAL D'ÉTUDES SPATIALES

ISAE

Institut Supérieur de l'Aéronautique et de l'Espace



Single Event Effects in 4T and 5T Pinned Photodiode Image Sensors

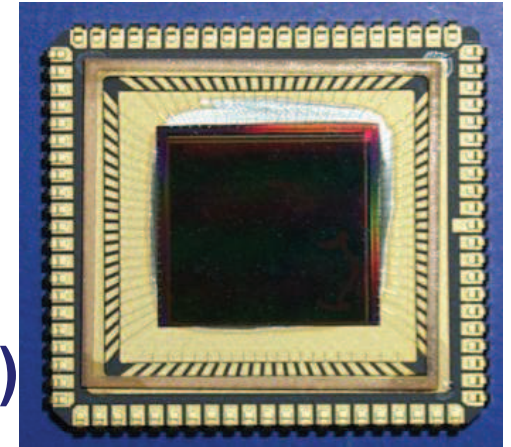
V. Lalluca, V. Goiffon, P. Magnan,

Univ. of Toulouse, ISAE, 31055 Toulouse, France

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CNES, 31401 Toulouse, France

- Image sensors in radiation environment
- Particularly the space imagers, e.g. :
 - Star trackers
 - Scientific imagers (SoloHi, Solar Orbiter ...)



- Undergo two classes radiation effects:

- Cumulative effects (TID, DDD)

- Single Event Effects (SEE)

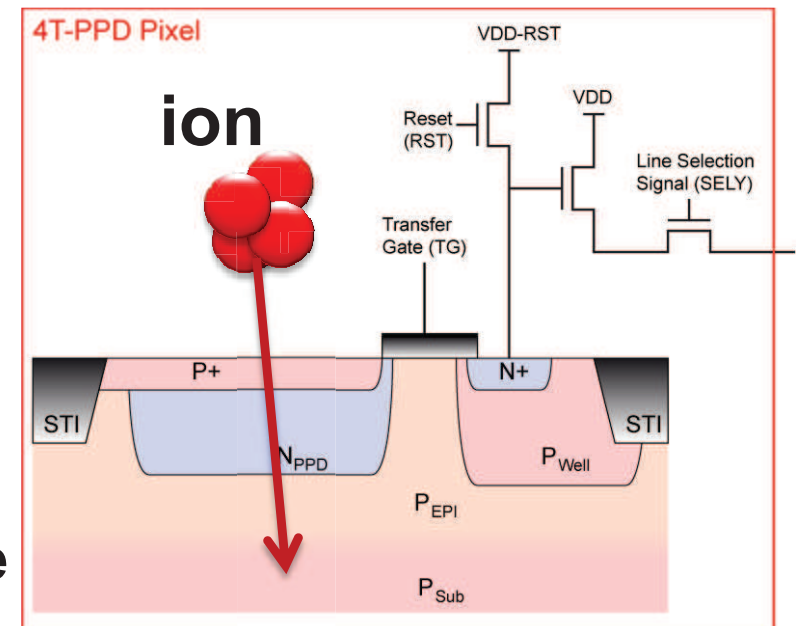
- Low Linear Energy Transfer (LET)

- High LET: Heavy Ions



 This study

Normal
 incidence

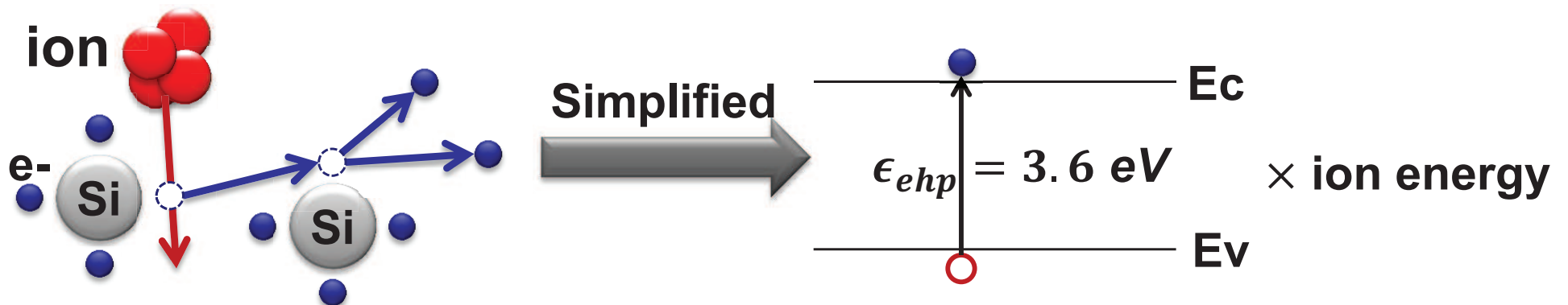


● Ionizing particles : Heavy ions

M/Q	Ion	Energy (MeV)	Depth (μm in Si)	LET ($\text{MeV.cm}^2/\text{mg}$)
5	N	60	59	3.3
5	Ne	78	45	6.4
5	Ar	151	40	15.9
5	Kr	305	39	40.4
5	Xe	420	37	67.7

● Interaction with silicon

● Complex but simplified: Mean energy for pair production

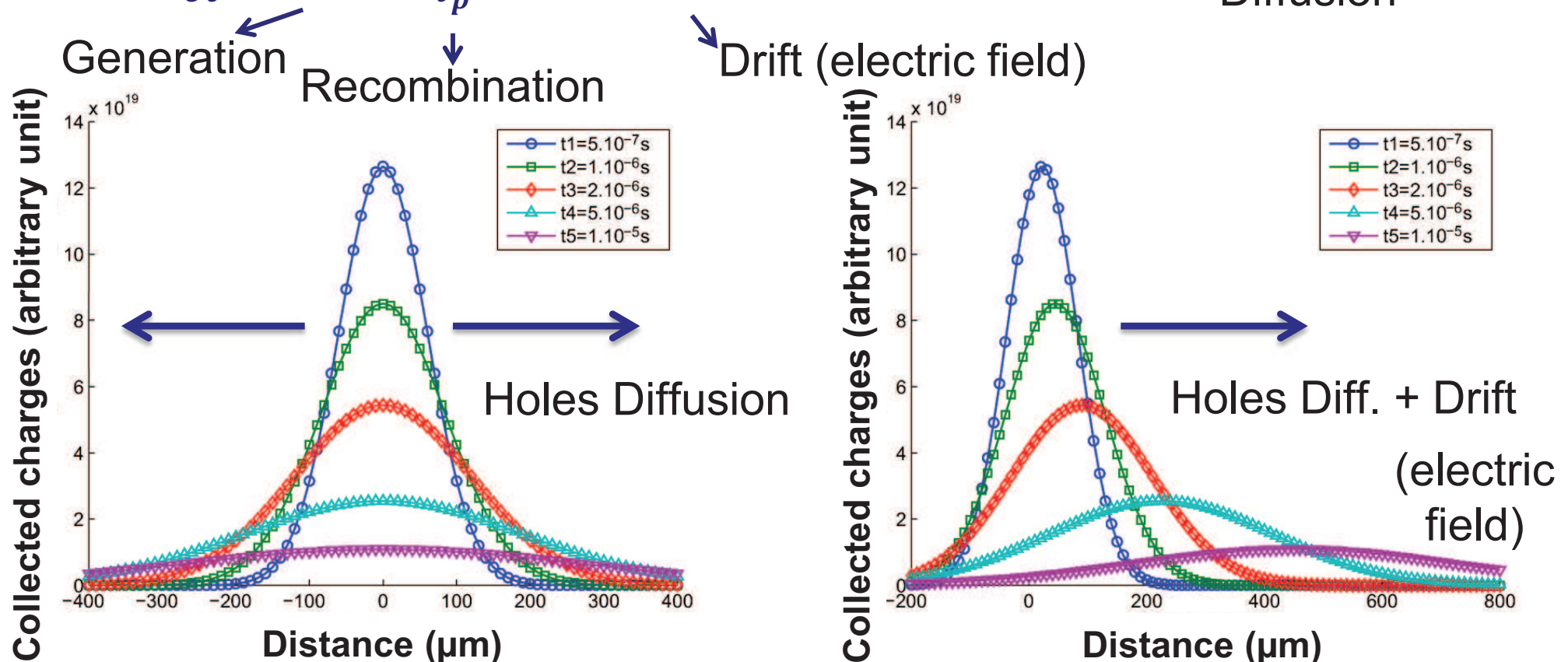


● Charge cloud in a semiconductor: transport equations

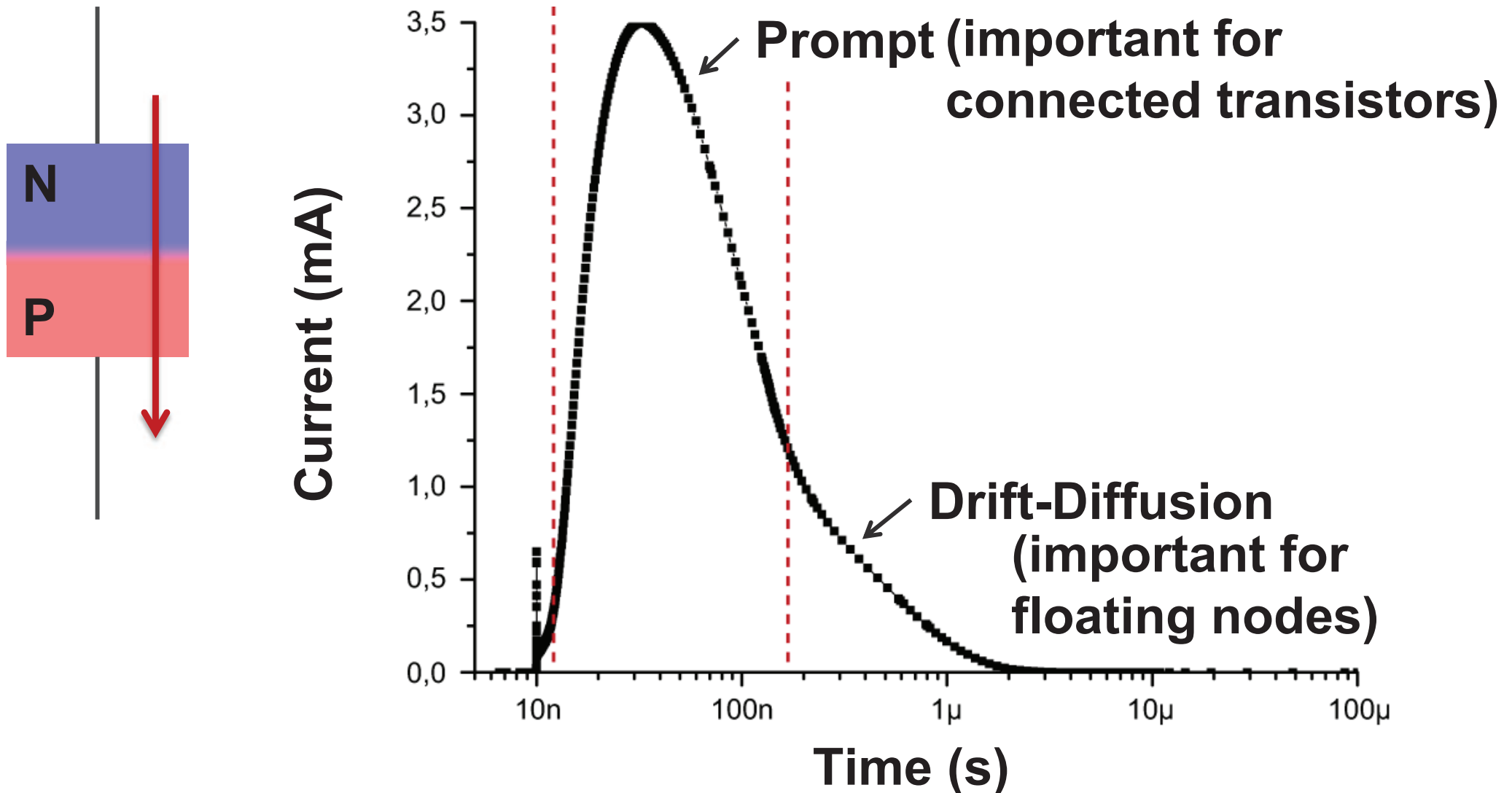
$$\bullet \frac{\partial n}{\partial t} = G_L - \frac{n-n_0}{\tau_n} + \mu_n \text{div}(n\vec{E}) + D_n \Delta(n)$$

$$\bullet \frac{\partial p}{\partial t} = G_L - \frac{p-p_0}{\tau_p} + \mu_p \text{div}(p\vec{E}) + D_n \Delta(p)$$

Diffusion



- Simulated results on a (2D) diode: parasitic current



- **Basic**

- Single Event Transient: analog devices
- Single Event Upset: digital devices (latch, memories)

- **Triggering of a low-impedance path**

- Single Event Latchup (parasitic thyristor)
- Single Event Snapback (parasitic bipolar)

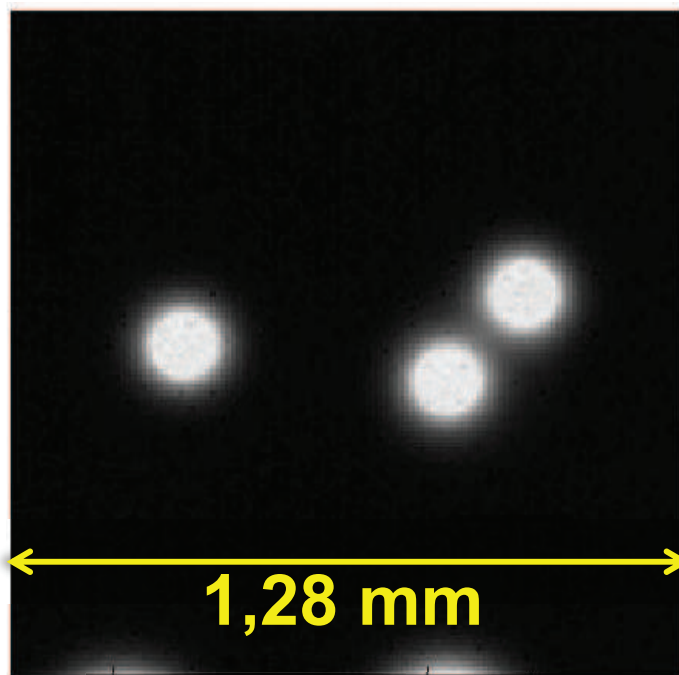
- **Thermal degradation**

- Single Event Gate Rupture
 - Single Event Dielectric Rupture
 - Single Event Burnout
- Thin oxides
High fields
Power devices

Potentially destructive

- In our last study : Single Event Effects (SEE) in 3T pixels
 - No functional interruption (no SEL/SES)
 - Single Event Transient (SET) effects
 - *No pixel design dependence*
 - *Bulk or epitaxial substrate dependence*

SETs on
 3T pixels
 Bulk
 substrate



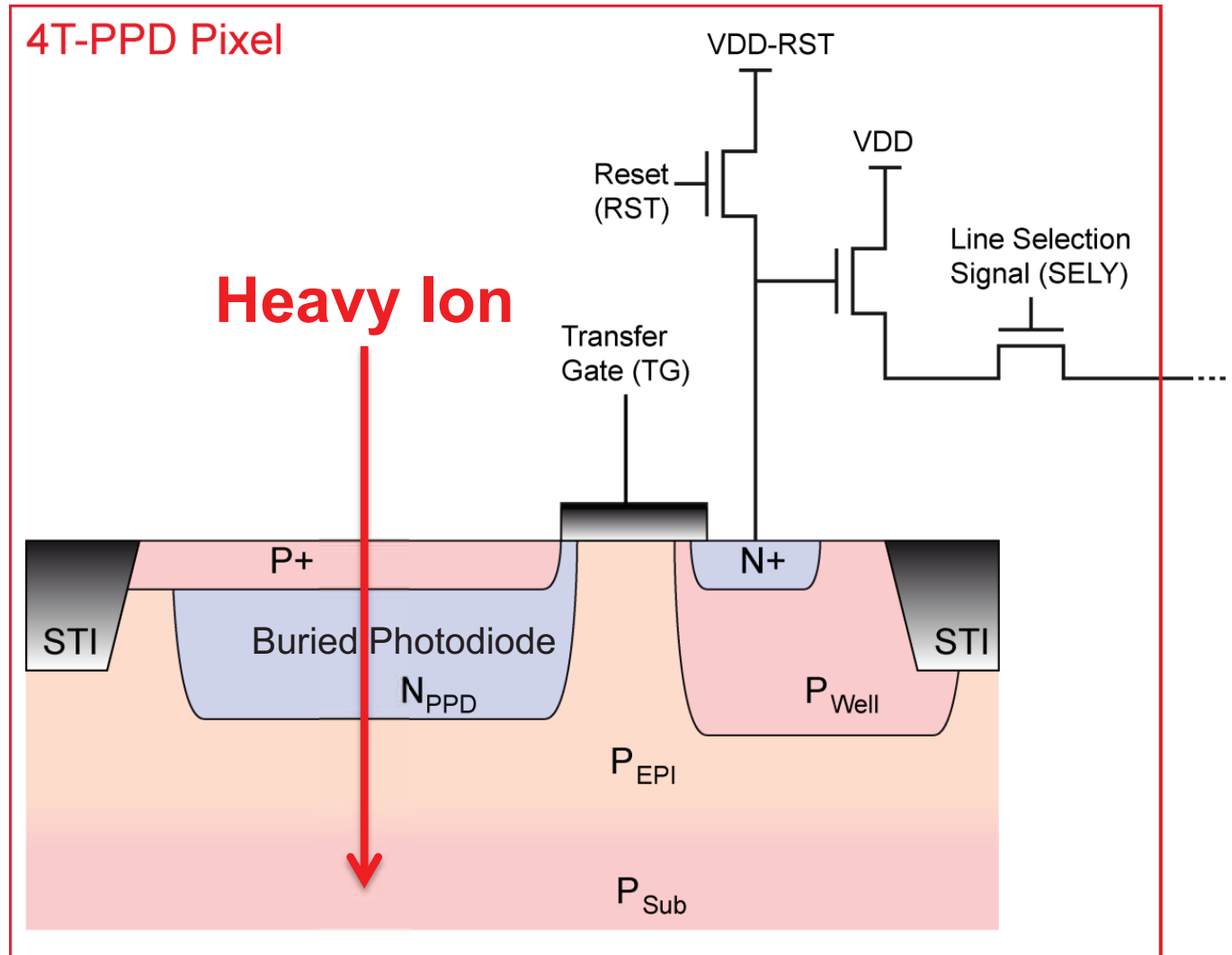
1,28 mm

SETs
 3T pixels
 Epitaxial
 substrate

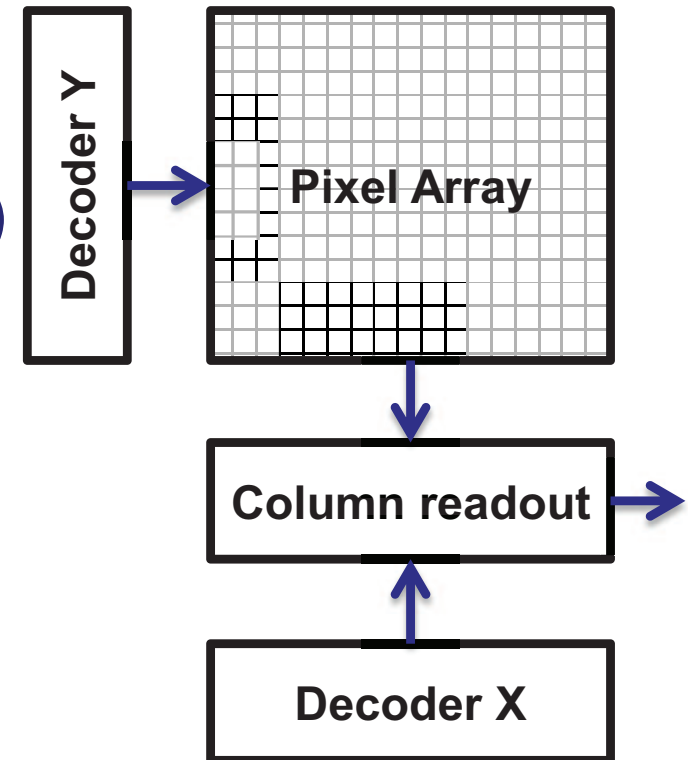


What about **4T pixels based on Pinned PhotoDiode (PPD)** ?

- Standard CMOS technology for circuits
- Dedicated implants for Pinned PhotoDiodes (PPD)
- 4T and 3T are different structures
- Yet, **few SEE studies on 4T-PPD CIS**



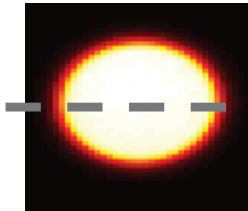
- “Basic” devices tested
 - Pixels
 - Address decoders (row and column)
 - Column readout circuits
- No on-chip “advanced” functions
 - No on-chip sequencer
 - No Analog to Digital converters



➡ Only SEE specific to CIS

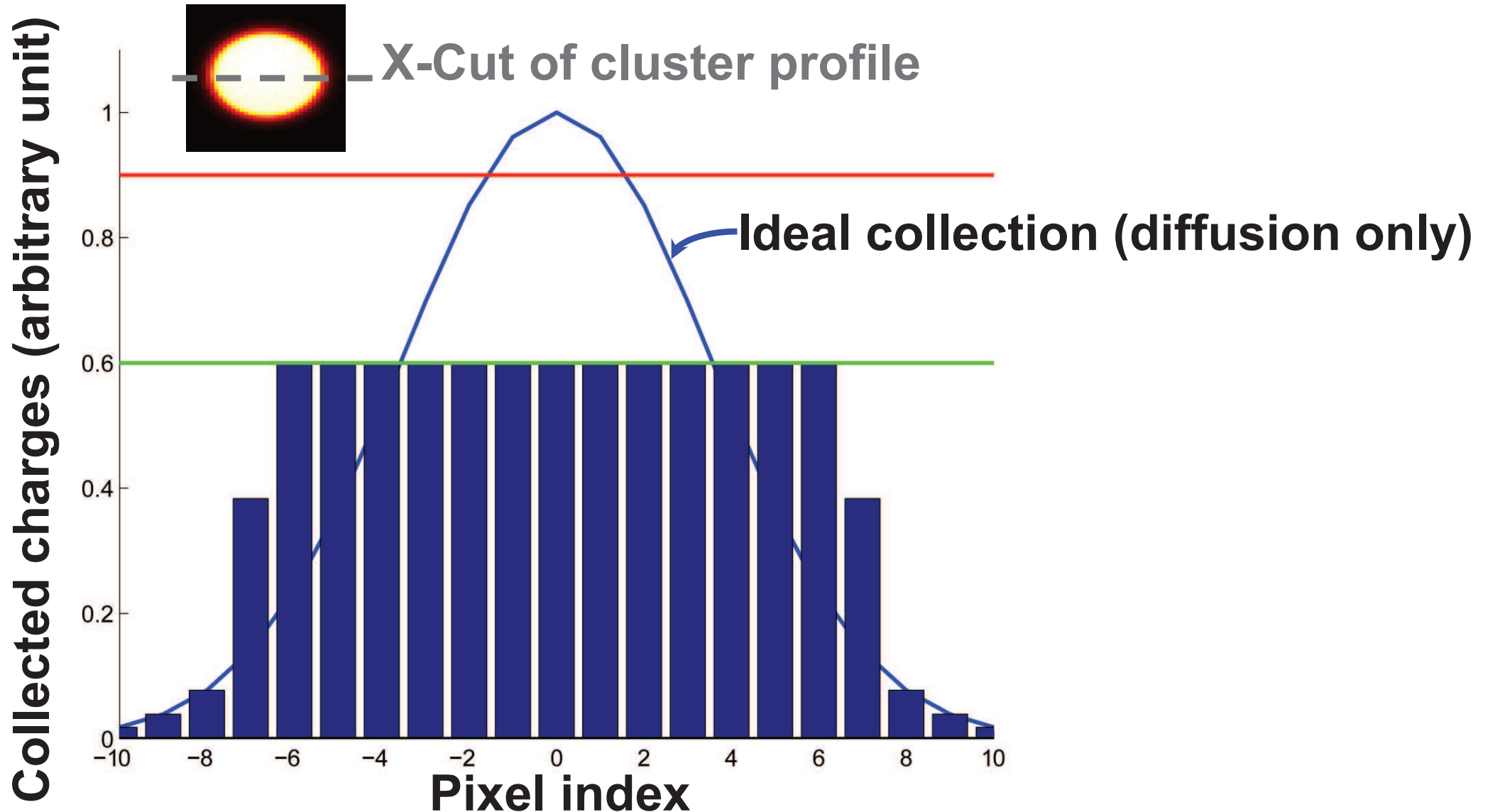
- Two sensors irradiated
 - CMOS Image Sensor A → Foundry A
 - CMOS Image Sensor B → Foundry B

- PPD has the lower saturation level

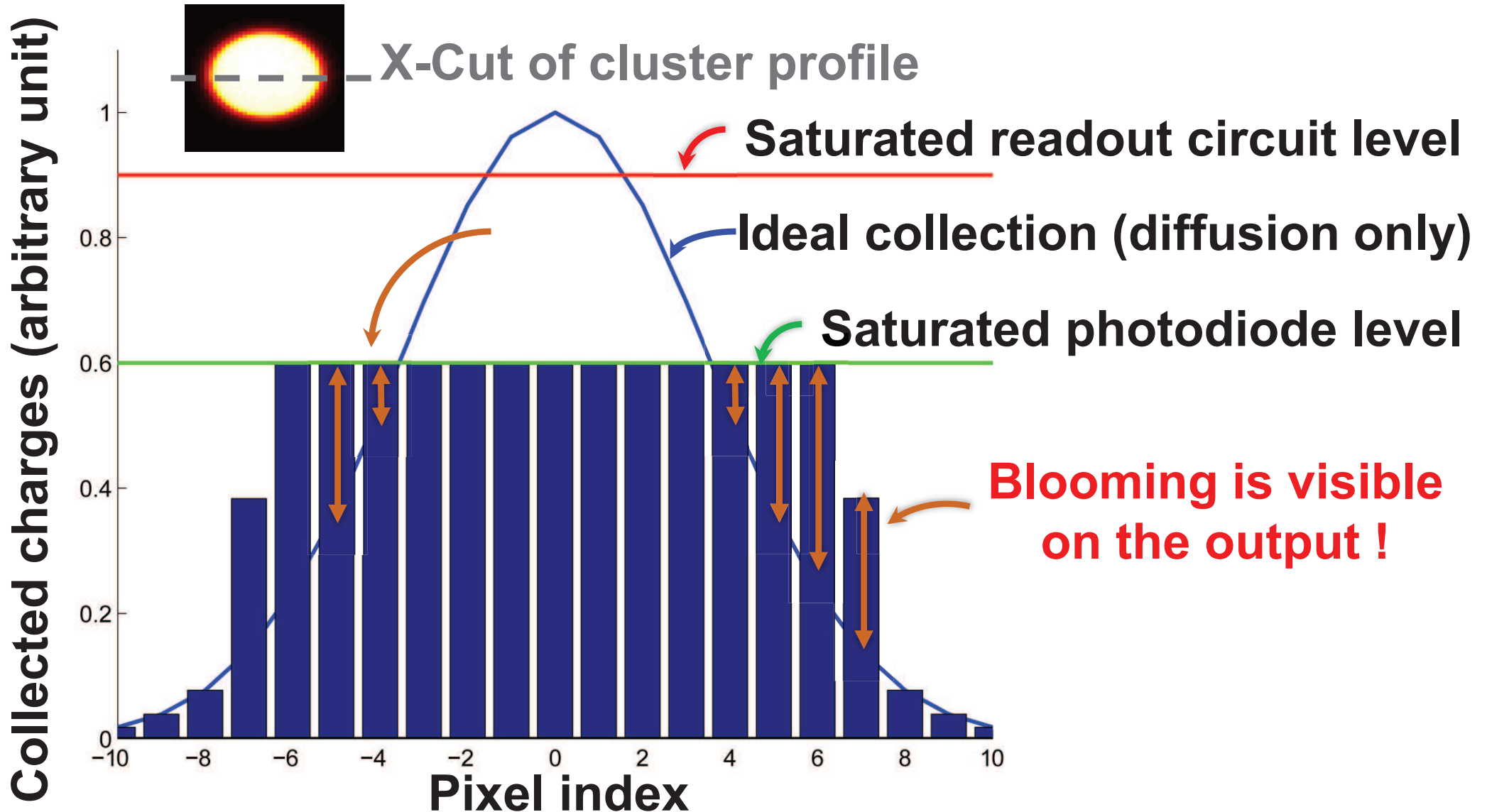


X-Cut of cluster profile

- PPD has the lower saturation level



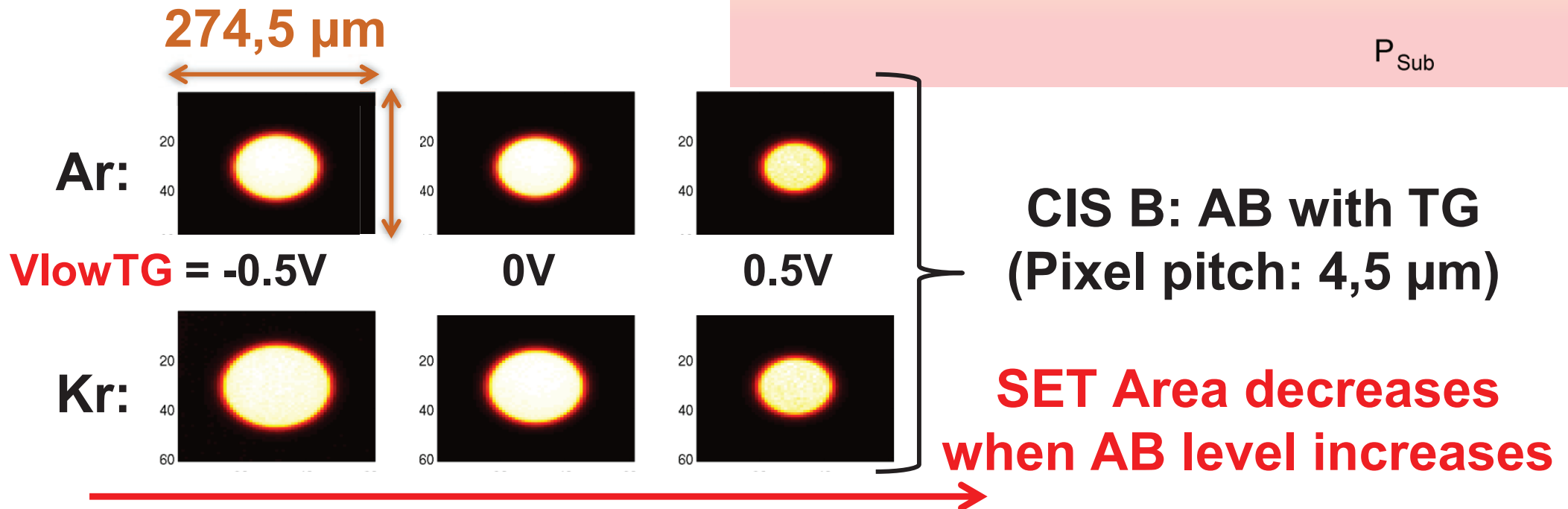
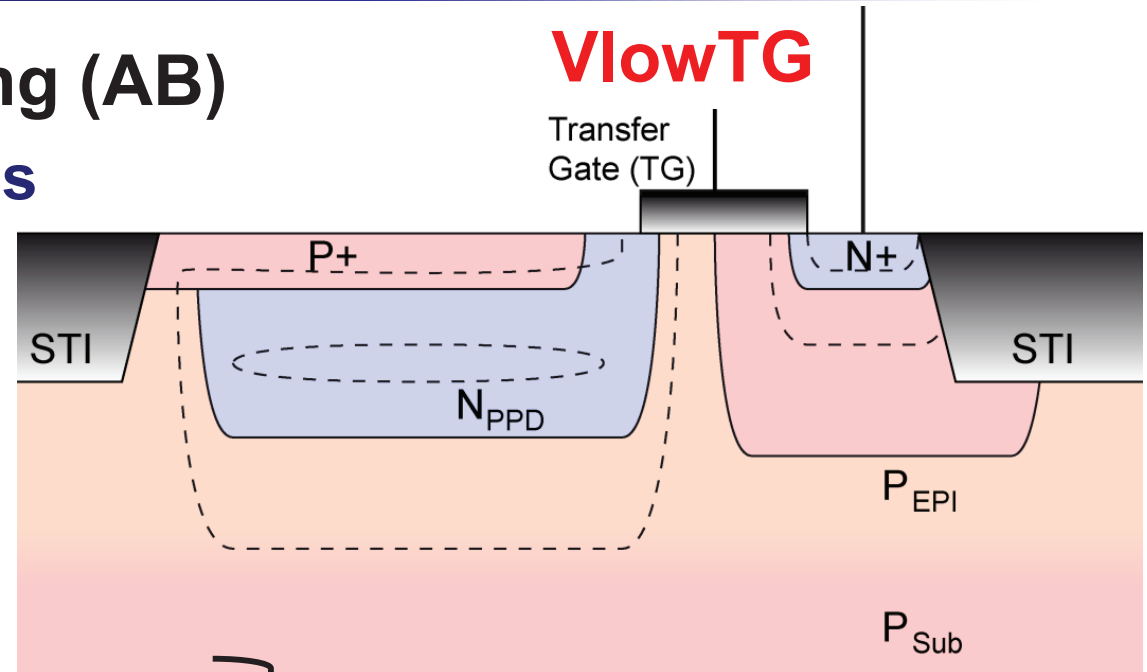
- PPD has the lower saturation level



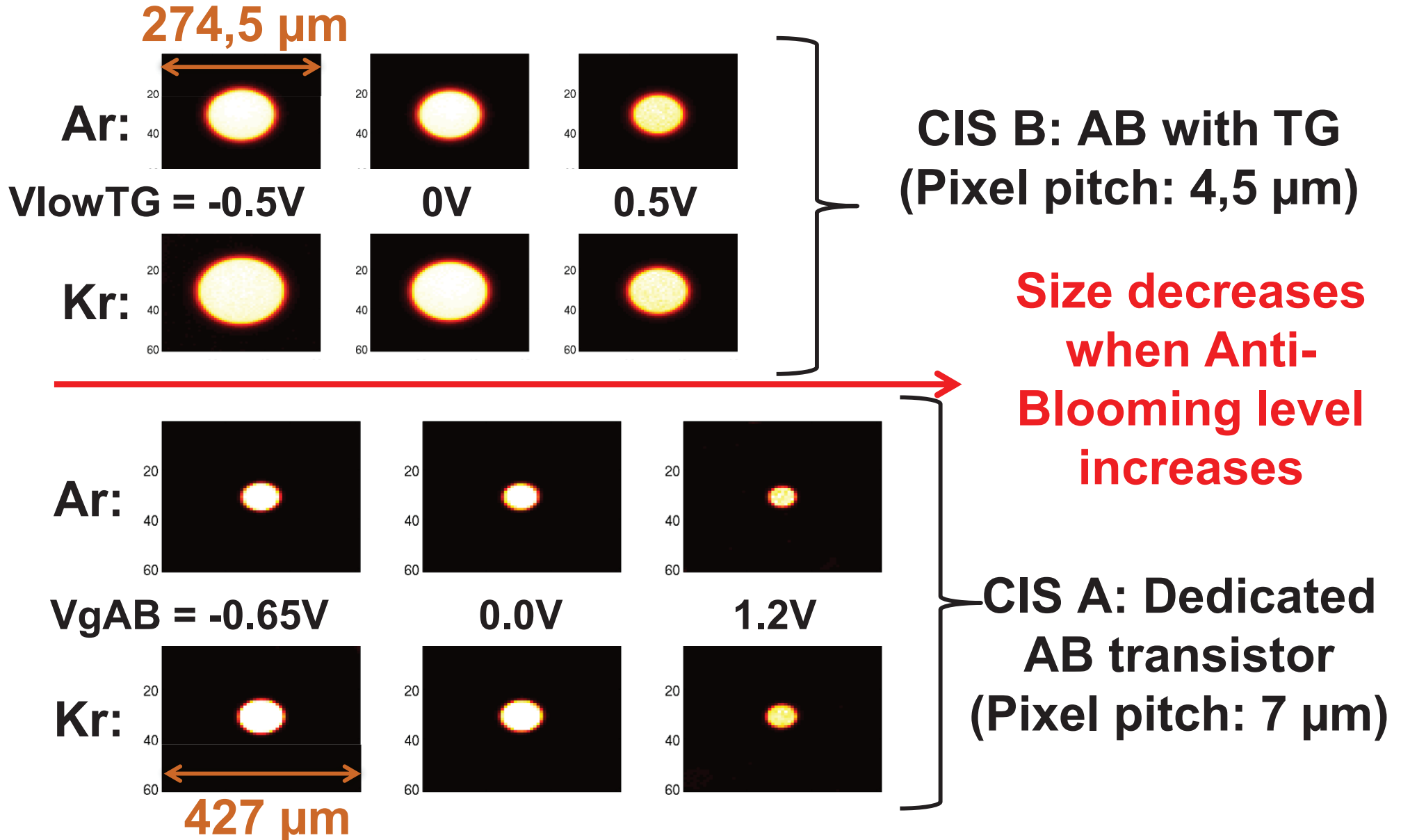
- Effect of the Anti-Blooming (AB)

- Using 2 different methods

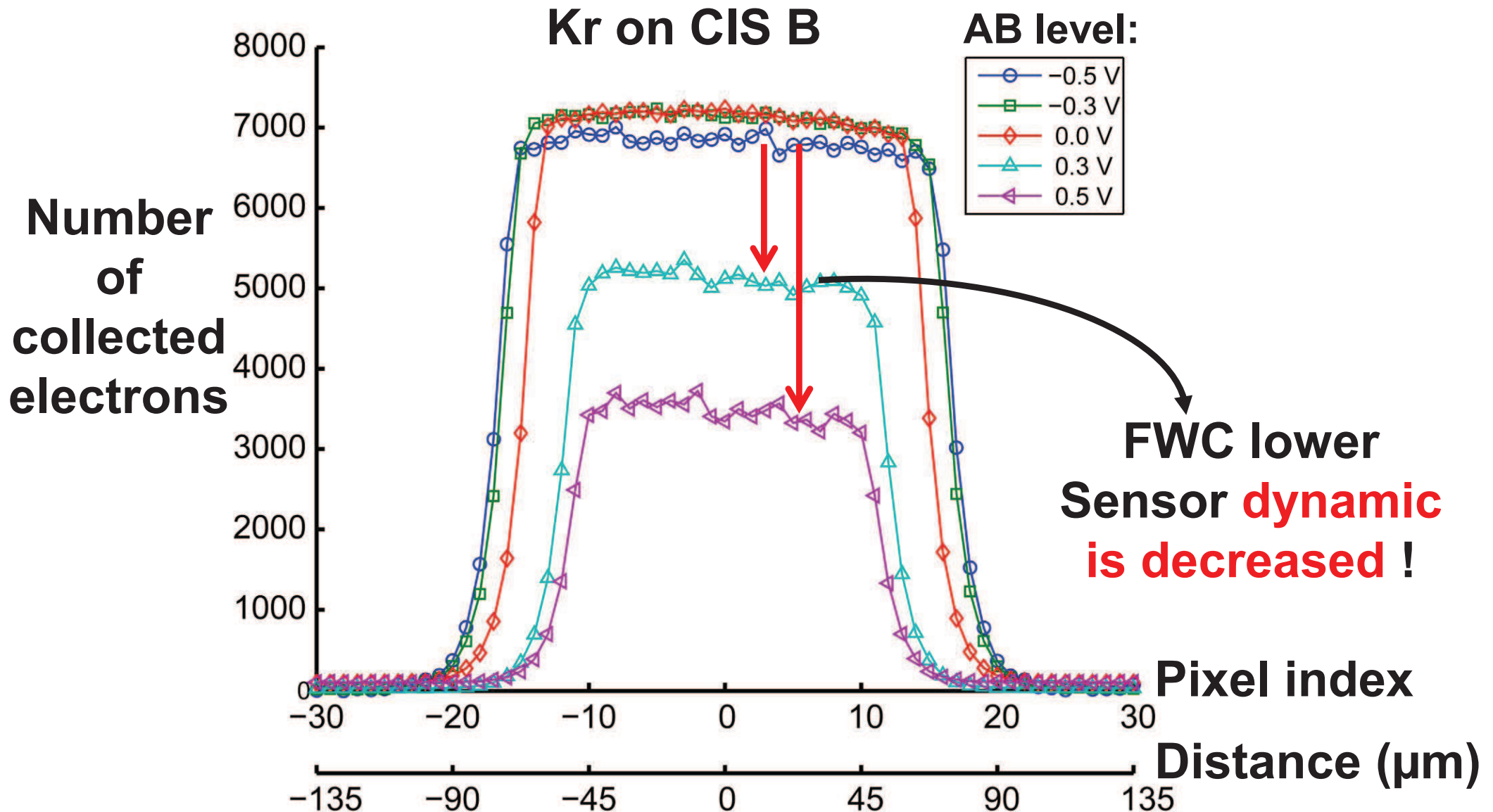
- With variation of the AB level



- Effect of the Anti-Blooming (AB) for 2 different methods



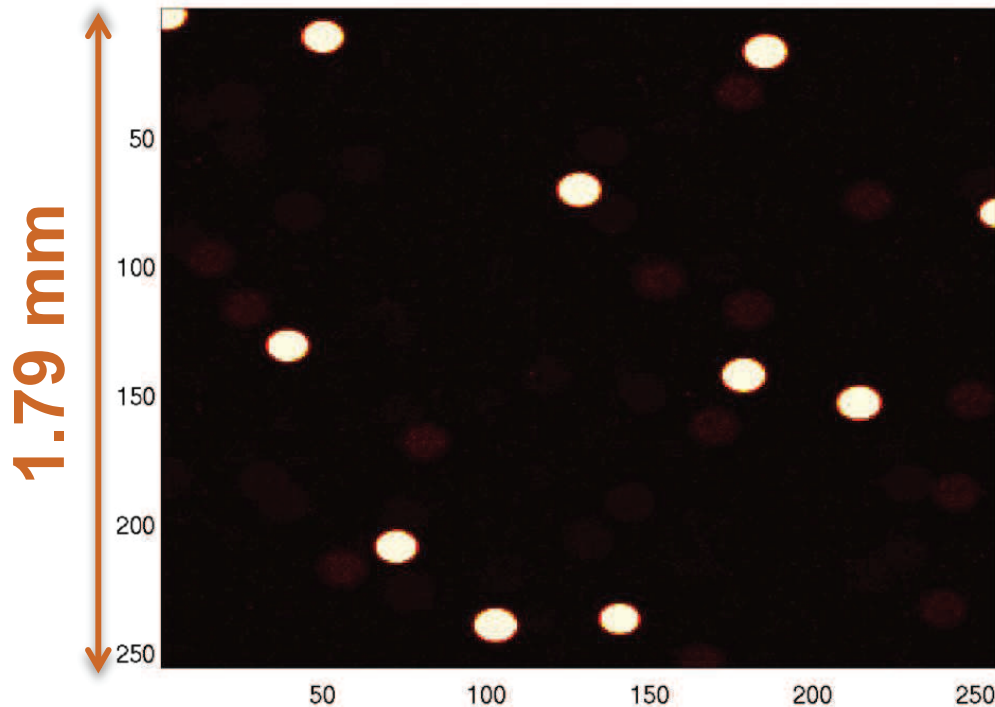
- **Decrease the Full Well Capacity** of the photodiode



Second effect : “black” row and injection

- Two CIS exposed to the ion flux

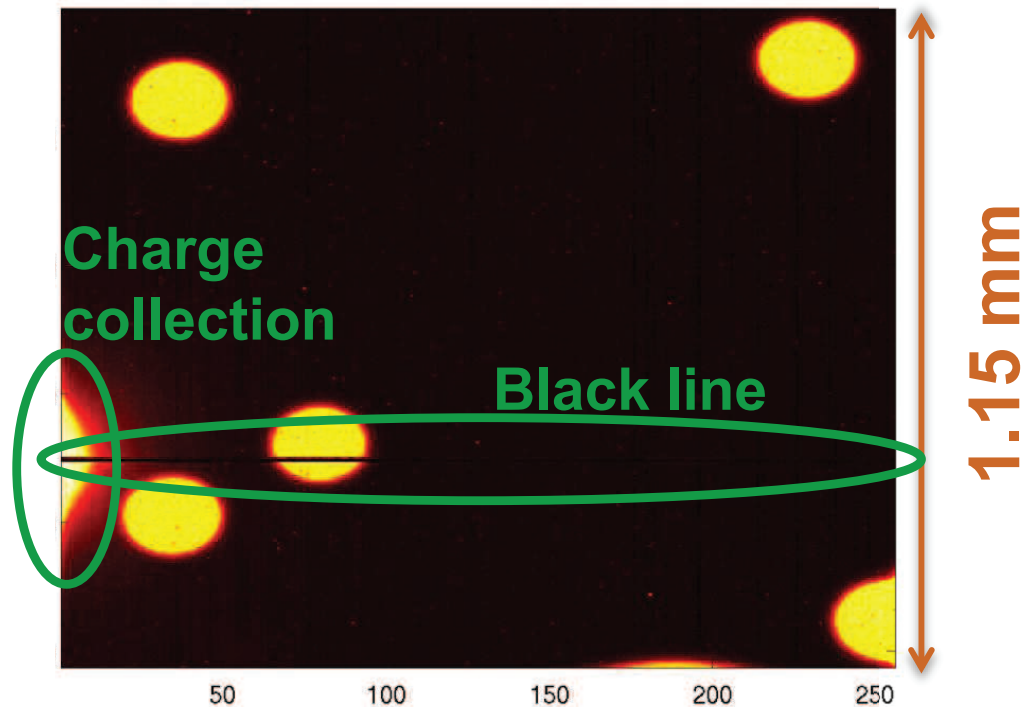
● Foundry A



**Xe on CIS A
(Higher LET)**

**No functional
problem**

● Foundry B

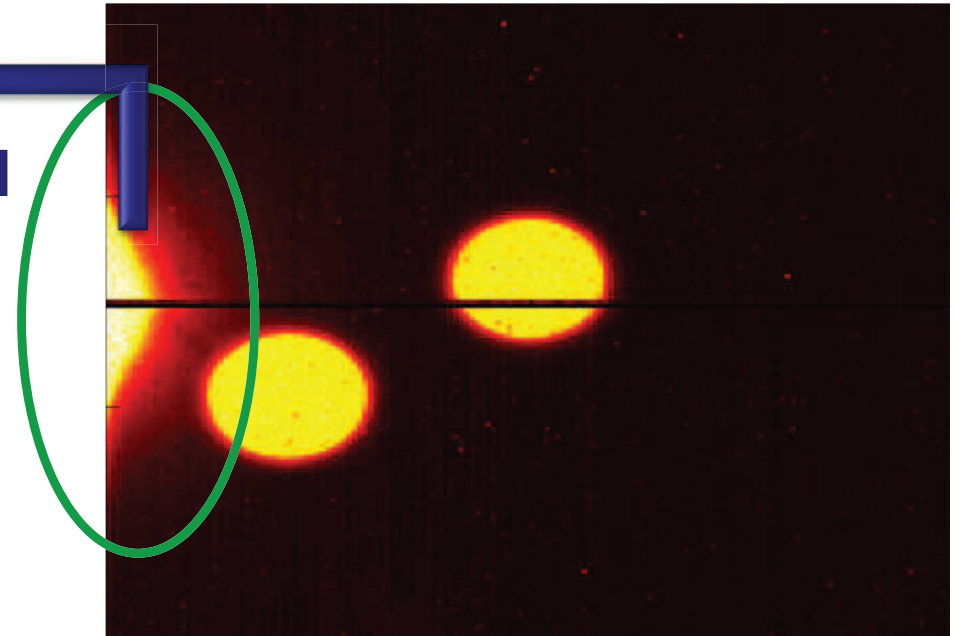


Kr on CIS B

**Random functional
problems until reset**

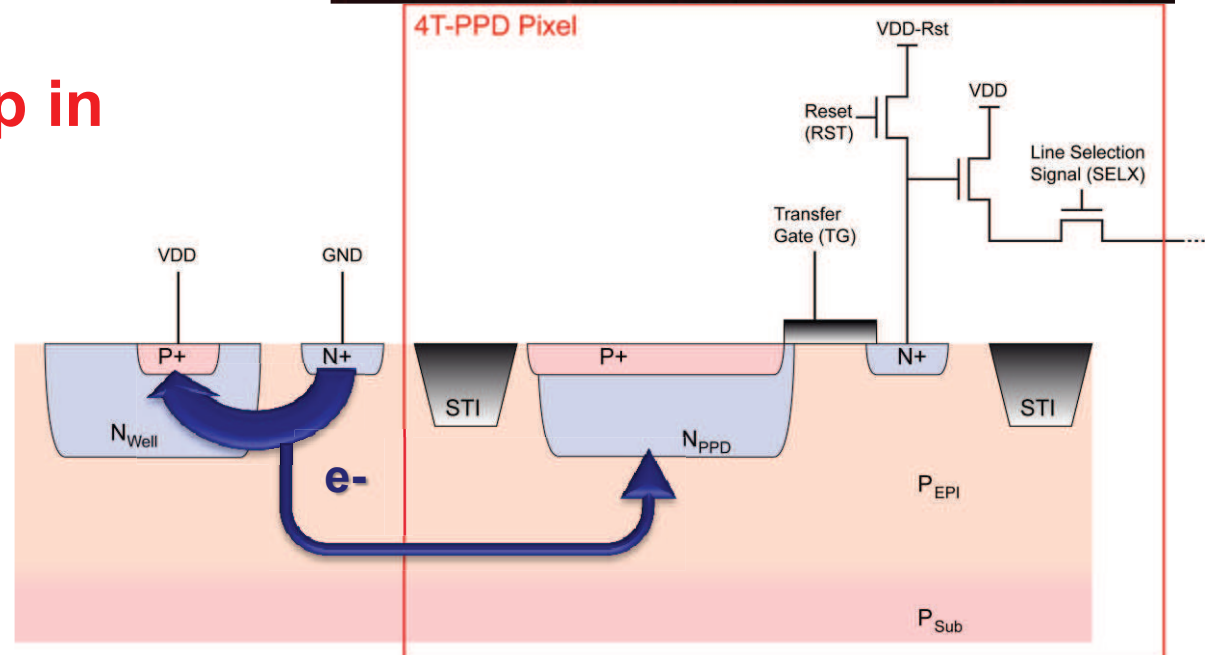
Second effect : “black” row and injection

- Collection of carriers
 - Nothing in MOSFET normal operation (image in dark)
- Hot carriers on the left part of the circuit



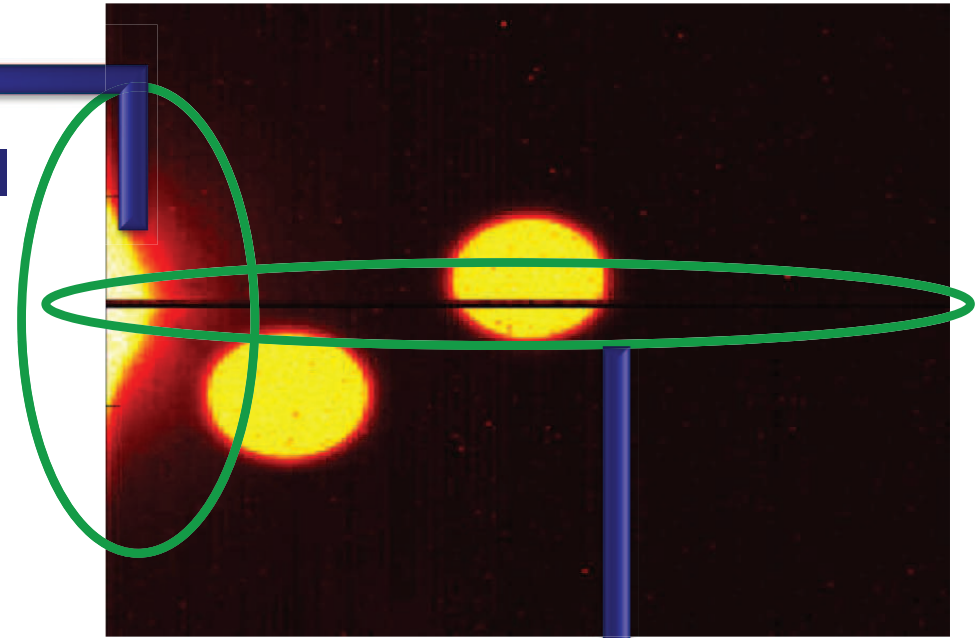
Single Event Latchup in address decoder

Not linked to 4T pixels !



Second effect : “black” row and injection

- **Collection of carriers**
 - Nothing in MOSFET normal operation (image in dark)
- ↓
- Hot carriers on the left part of the circuit



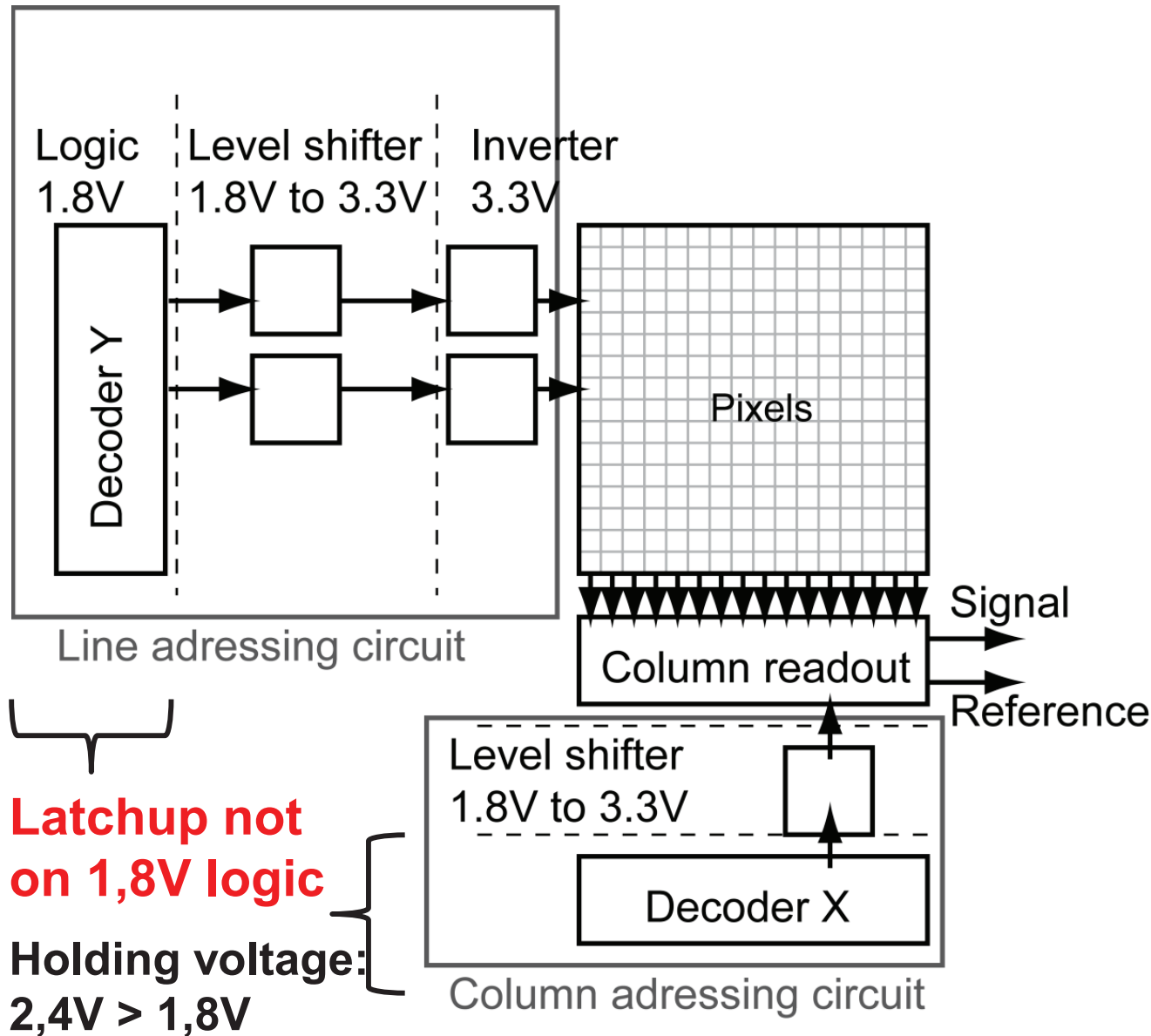
↓

Single Event Latchup in
address decoder

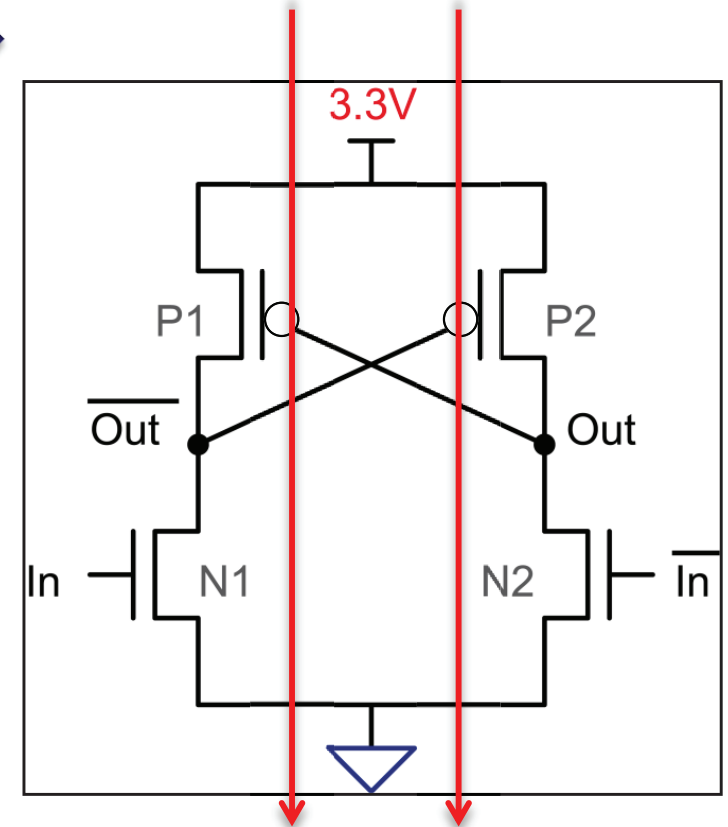
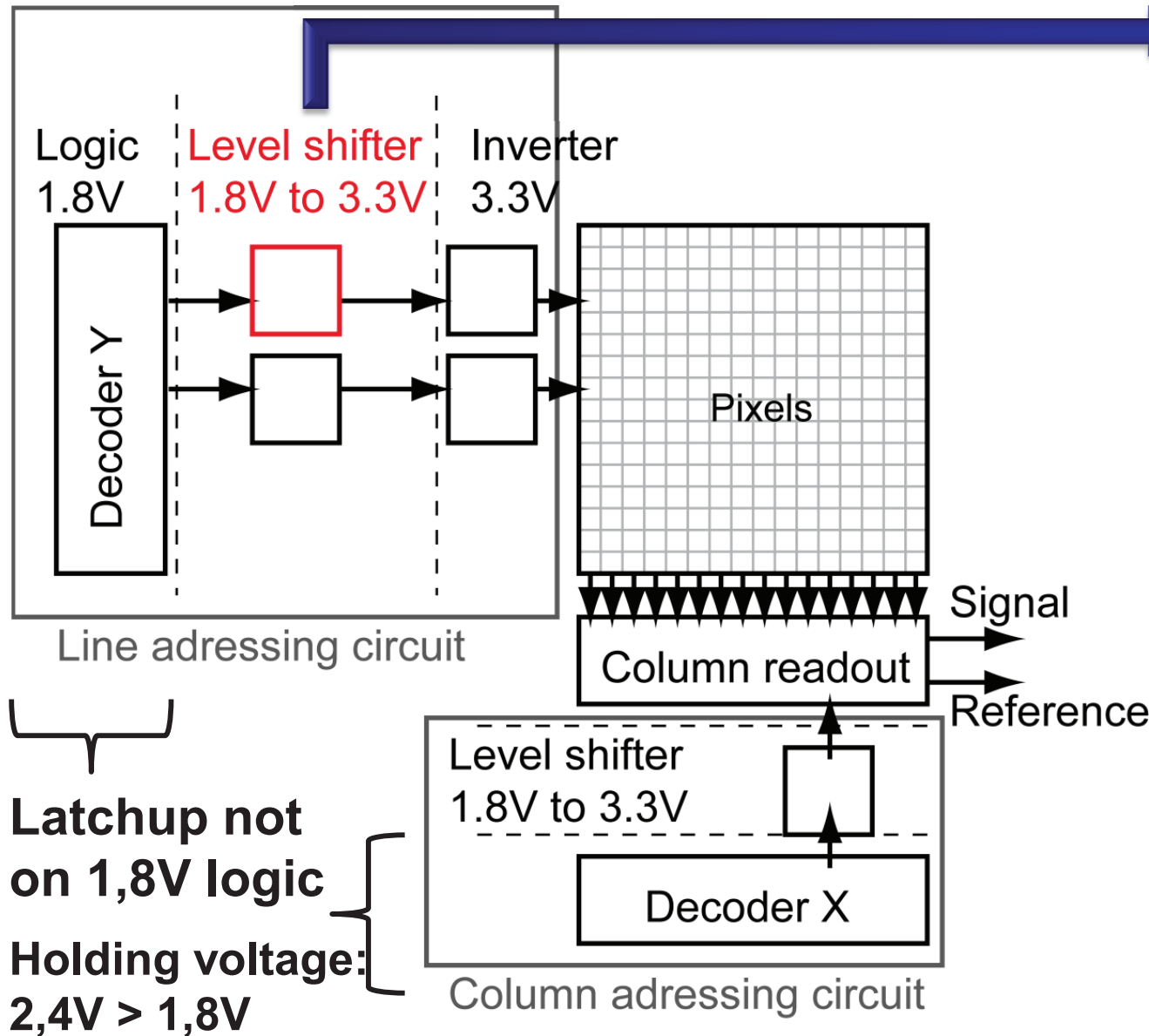
↑

- **Black rows**
 - Selection signal is wrong
 - Address decoder is no longer fully functional

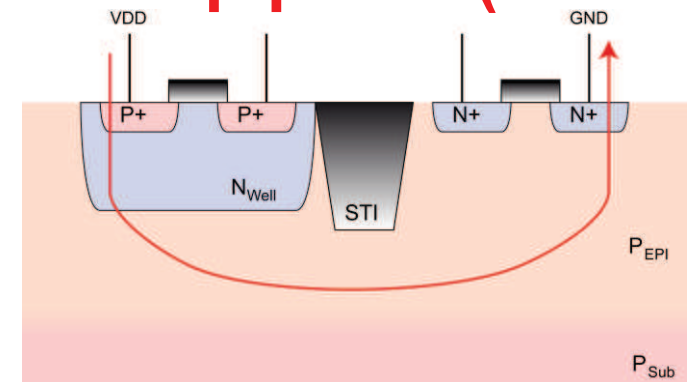
Single Event Latchup: localization



Single Event Latchup: localization

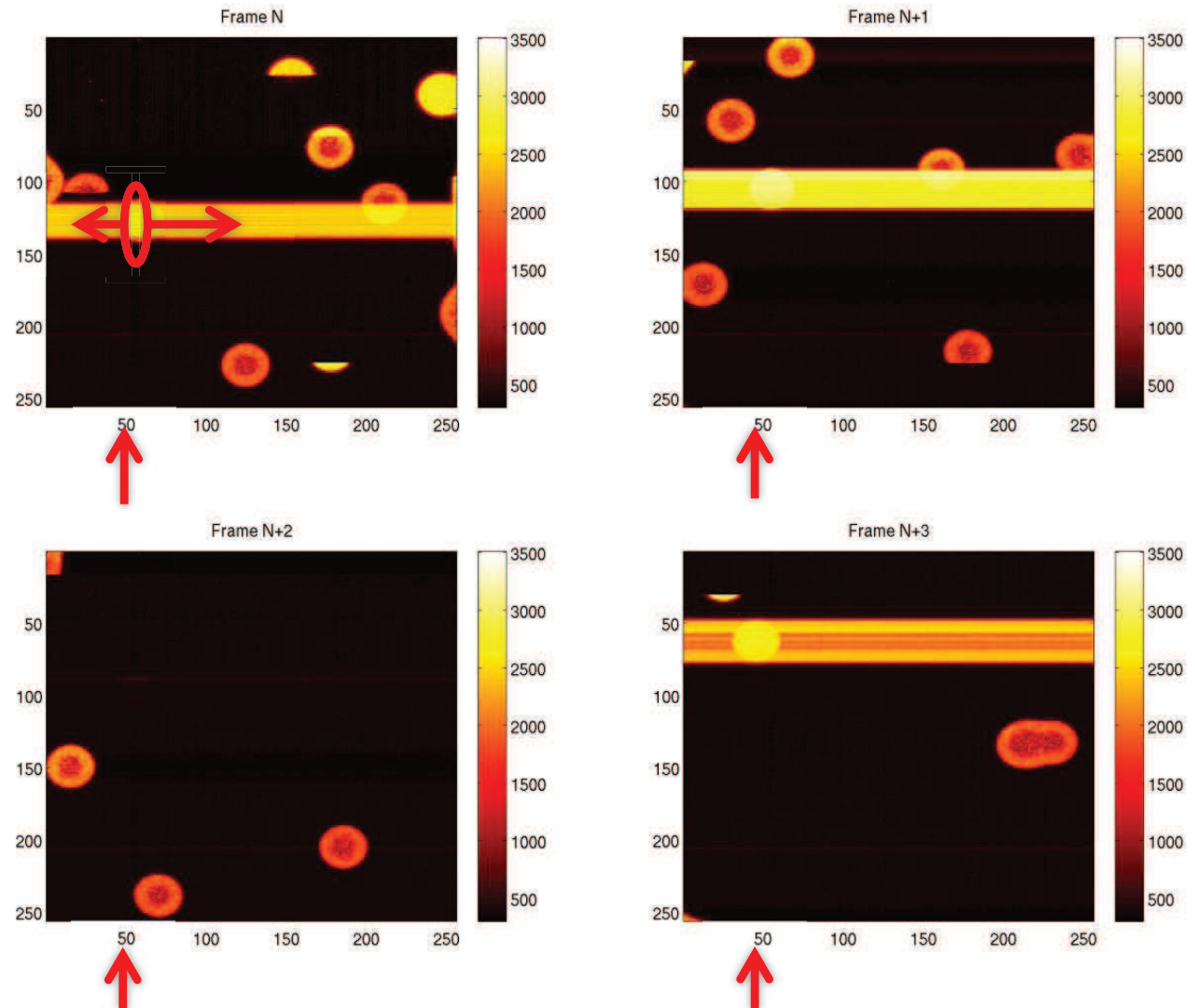


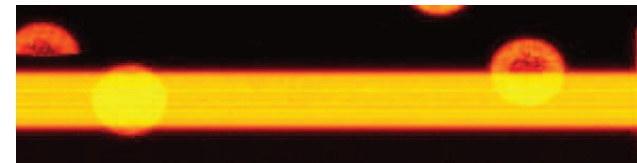
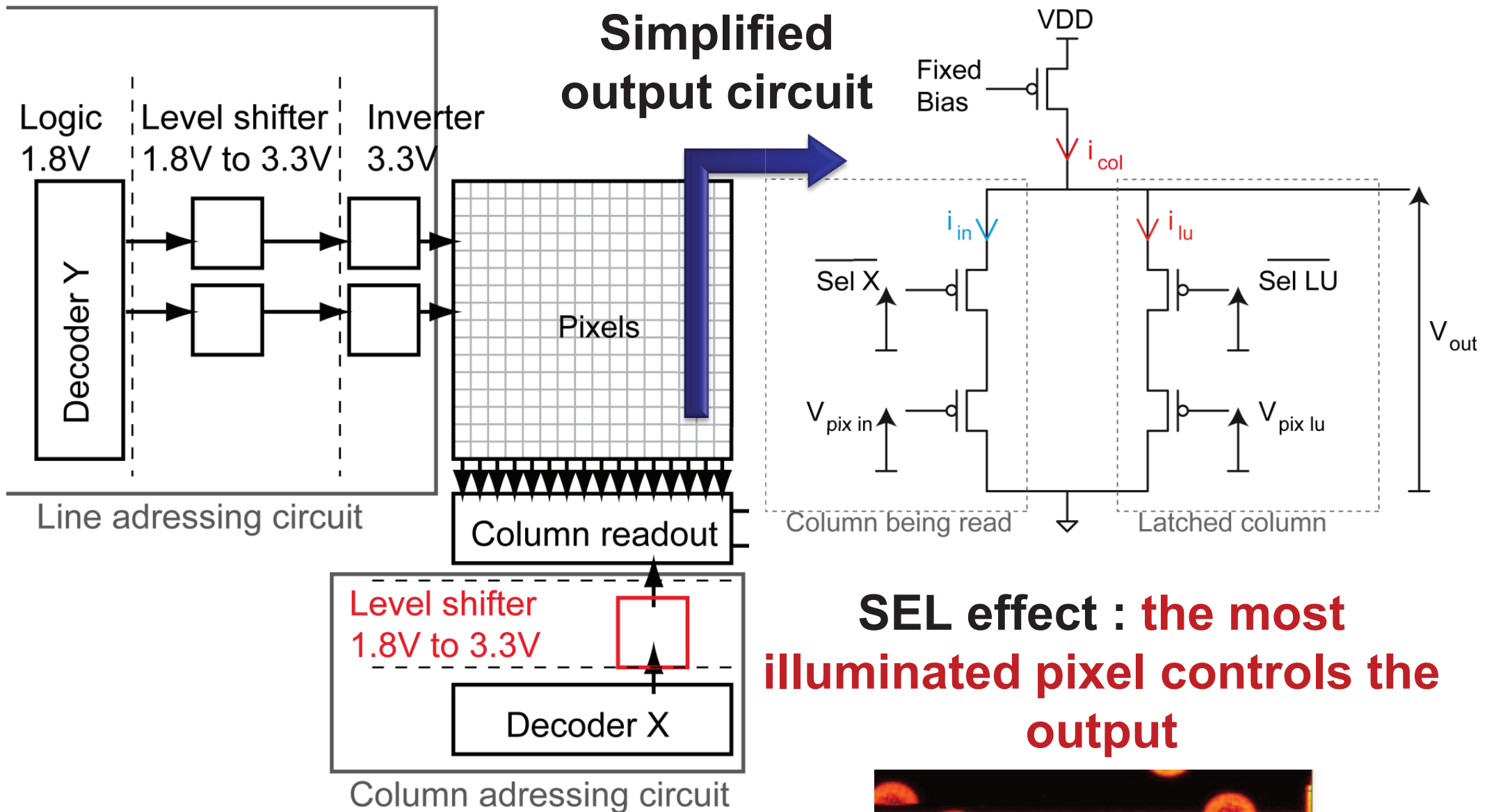
Latchup paths (PNPN)



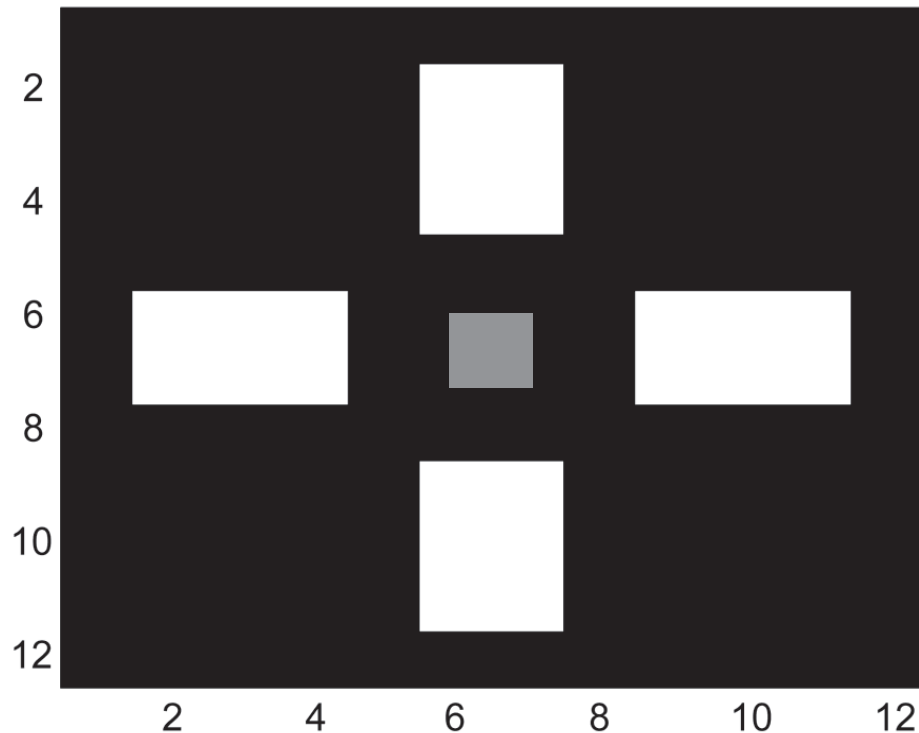
Third effect : Bands

- Illuminated bands starting randomly during irradiation
- Always involves a SET on the same column (50 here)
- Band effect disappear only when power is reset

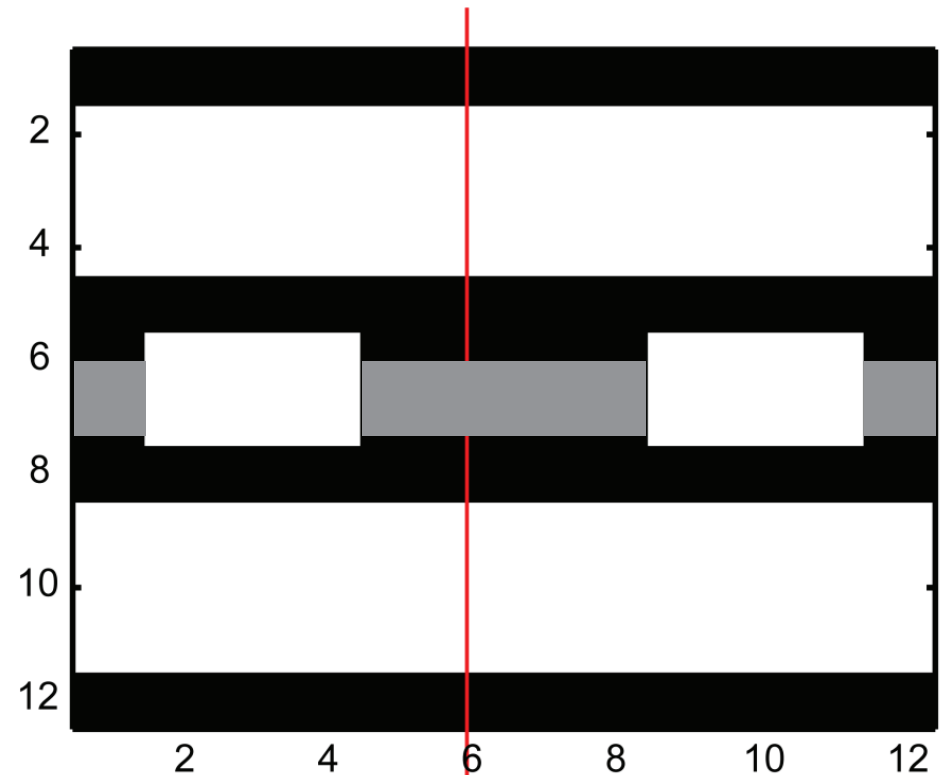




- Frames are no longer the real image
- Example: In the case of an illuminated pattern



Non Latched



Latched on 6th column

Pattern cannot be recognized !

- **Single Event Latchup**



- **Functional interrupts**
 - **Until reset of power**
- **Black rows / hot carriers**
- **Column always connected**
- **Effects stack !**



- **Mitigation :**
 - **Operational: low supply**
 - **Design: Guard rings, P and NMOST distance**
 - **Process: thin epi. layer**

- **Single Event Transient**



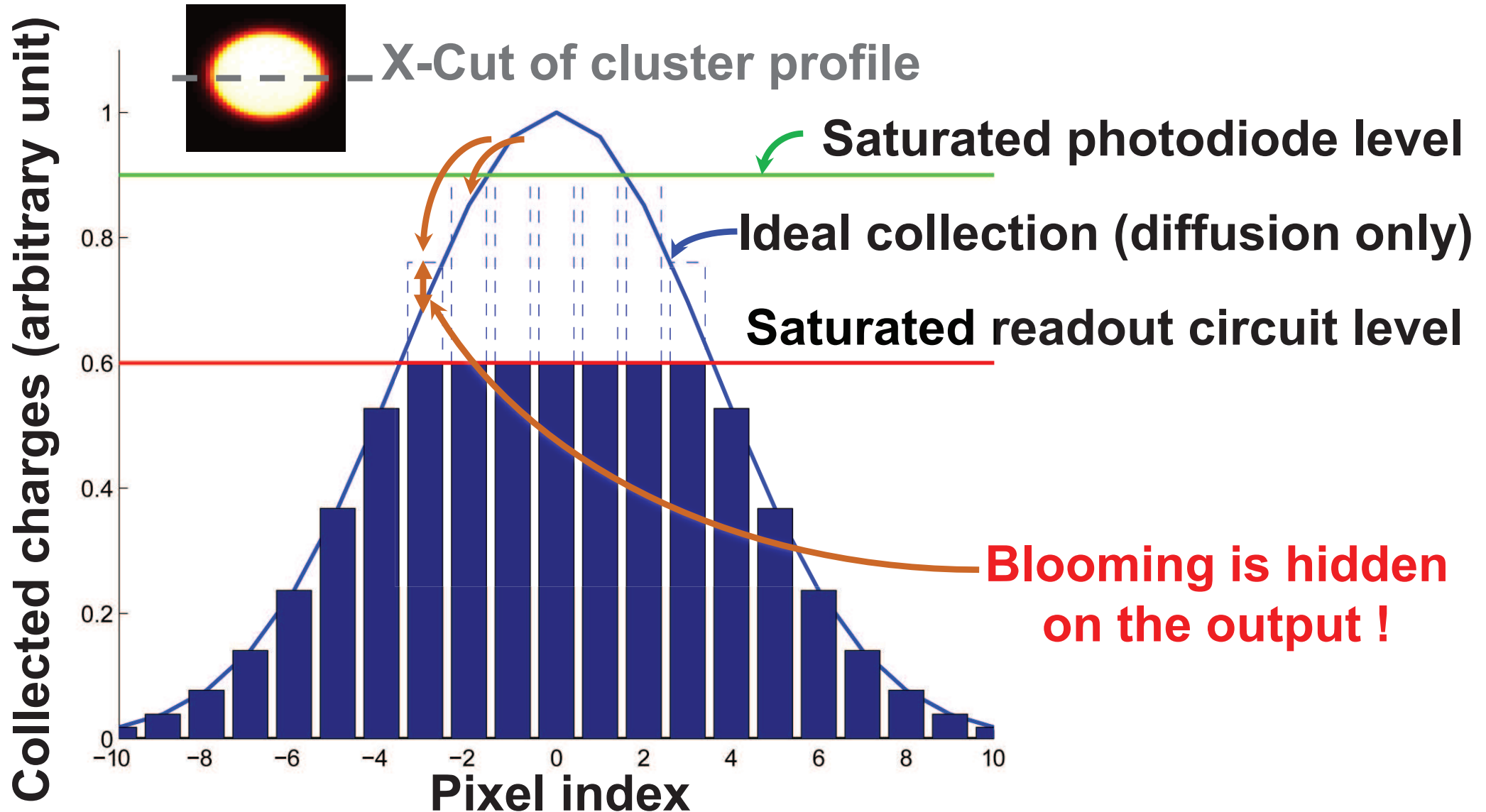
- **Frame perturbation**
 - **One frame, several frames when sensor has lag**
- **Pixel collecting charges (diffusion and blooming)**



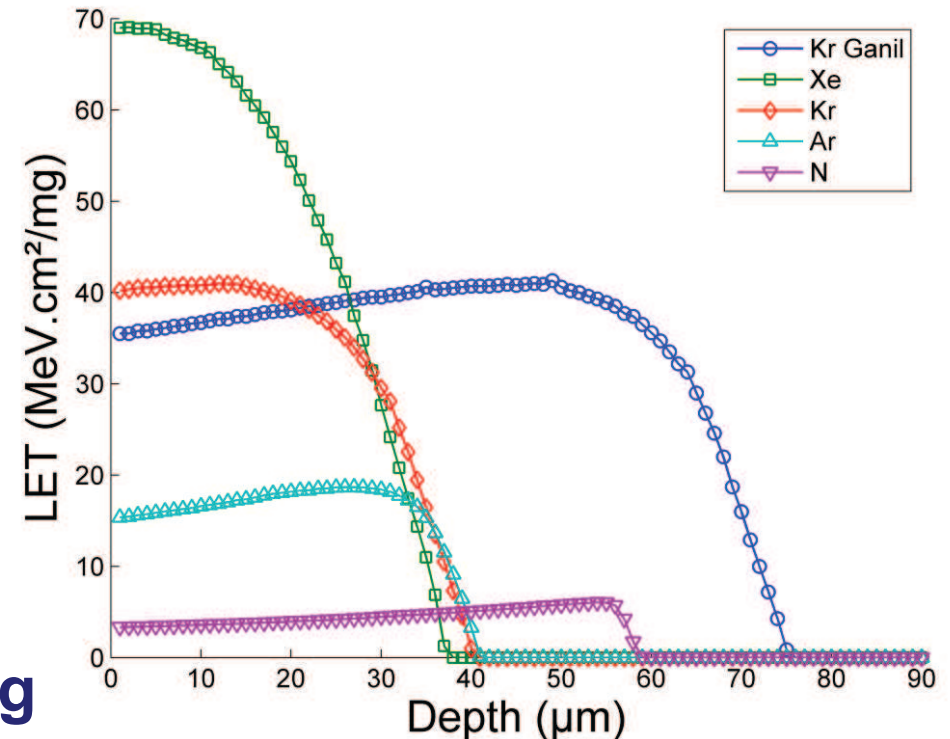
- **Mitigation :**
 - **Anti-blooming**
 - *Two methods used here*
 - **Diffusion**
 - *Thinner epitaxial Layer*

Thank you !

- 1st case: lower saturation level due to readout circuits



- **Several arrays tested**
 - CMOS 0,18 μm
 - 4T PPD
 - 256 x 256 pixels
- **Heavy ions : N, Ar, Kr, Xe**
 - Energy : 60 to 611 MeV
 - LET : 3,3 to 67,7 $\text{MeV.cm}^2/\text{mg}$
 - Normal Incidence
- **Only the sensor area is exposed**
 - Digital conversion outside the sensor
 - Frame grabbing outside the sensor



Energy deposited by each ion versus depth in Si

SEE from the imager only